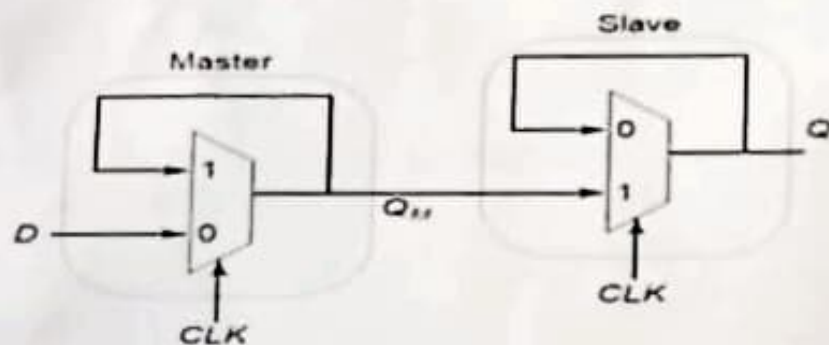


**Final Assessment Test (FAT) - APRIL/MAY 2023**

Programme	<b>B.Tech</b>	Semester	<b>Winter Semester 2022-23</b>
Course Title	<b>VLSI SYSTEM DESIGN</b>	Course Code	<b>BECE303L</b>
Faculty Name	<b>Prof. Ananthiah Durai S</b>	Slot	<b>B1+101</b>
		Class Nbr	<b>CH2022235001207</b>
Time	<b>3 Hours</b>	Max. Marks	<b>100</b>

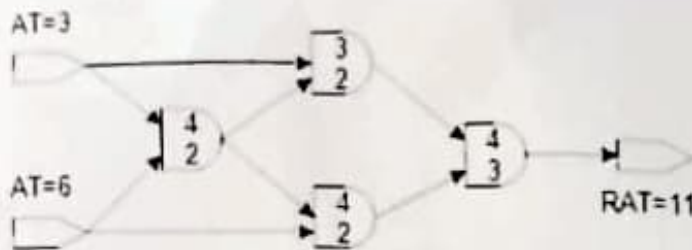
**Section A (9 X 10 Marks)**
**Answer All questions**

01. a) Derive an expression for the drain current of an N-channel enhancement type MOSFET from the first principles. Draw the transfer and output I-V characteristics of the transistor. (7 Marks) [10]  
 b) From the drain current expression at the saturation region, comment on how to increase the current for a fixed gate-to-source voltage. (3 Marks)
02. Consider the NMOS transistor in a 0.65  $\mu\text{m}$  process with  $W/L = 1.95/0.65$ . In this process, the gate oxide thickness is 11 nm, and the mobility of electrons is  $350 \text{ cm}^2/\text{Vs}$ . The threshold voltage is 0.75 V. Plot  $I_{ds}$  vs.  $V_{ds}$  for  $V_{gs} = 0, 1, 2, 3, 4$ , and 5 V. Assume five different  $V_{ds}$  values to get smooth  $I_{ds}$ . [10]
03. A positive edge-triggered register on a Master-Slave configuration is shown in Figure 1. Implement the same using transmission gates. Briefly explain how the 'clock load per transistor' can be reduced using a modified diagram (7+3 Marks) [10]


**Figure 1**

04. An NMOS inverter with a saturated load is shown in Figure 2. Draw the cross-sectional diagram of the same. With neat sketches, explain the fabrication process flow of the device using a self-aligned poly-gate process. We know that a typical fabrication of a CMOS inverter requires 6 photo masks. How many masks will be required to realize this inverter? Assume either positive or negative tone photo-resist. Does the inverter fabrication require a 'p-well,' 'n-well,' or 'twin-well' process? Comment on the same. Note: You may ignore the bulk diffusion and consider only 3-terminals for FETs. [10]





**Figure 4**

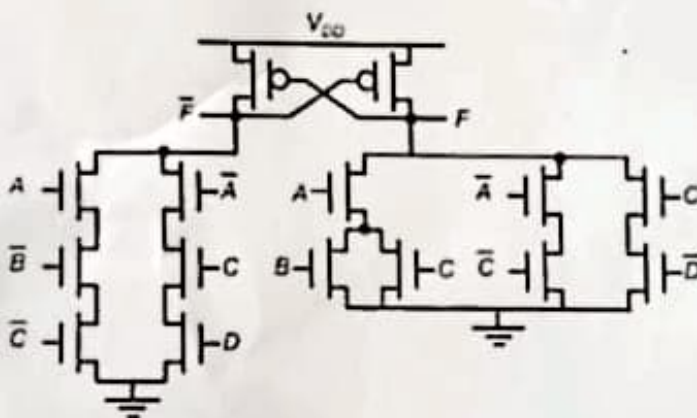
b) With a neat sketch of the waveform, elaborate the Setup Time & Hold time calculation for an RTL circuit with launch & Capture Flops. (5 Marks)

09. With neat sketches, explain how "read" and "write" operations are carried out in a CMOS 6T-SRAM cell. Write the conditions on sizing for proper "read" and "write" operations considering the 300 nm technology node. [10]

**Section B (2 X 5 Marks)**

**Answer All questions**

10. The circuit shown in Figure 5 is realized using Differential Cascode Voltage Switch Logic (DCVSL). Construct a truth table with the input variables A, B, C, and D and identify the function implemented by F and  $\bar{F}$ . [5]



**Figure 5**

11. Enumerate the various stages that must be traversed throughout the physical design flow of an Integrated Circuit (IC) before the specifications can be taped out. [5]

**OR**

Discuss the various stages and challenges involved in the 'design to realization' of a MEMS microsensor system.

